Seat	t No :	Enrolment No.	
Sea	. 110	GUJARAT TECHNOLOGICAL UNIVERSITY ME – SEMESTER I (NEW) – • EXAMINATION – SUMMER 2016	
Subject Code: 2710808 Date:19/05		2016	
Tin	ne:02	Name: Advanced Metrology and Experimental Techniques :30 pm to 05:00 pm Total Marks:	70
Inst	2.	Attempt all questions. Make suitable assumptions wherever necessary. Figures to the right indicate full marks.	
Q.1	(a) (b)	Discuss the need for high precision measurement. Enlist methods of improving accuracy and surface finish. Explain any one in detail.	07 07
Q.2	(a) (b)	Classify errors. Discuss their causes. The following readings were obtained during temperature measurement: 39.6, 39.9, 39.7, 39.9, 40.0, 39.8, 39.9, 39.8, 40.4 and 39.7 °C Calculate: The mean, standard deviation and range. OR	07 07
	(b)	Discuss general considerations in Data analysis.	07
Q.3	(a) (b)	Discuss experiment design factors. Explain experiment design protocols with suitable example. OR	07 07
Q.3	(a) (b)	Explain the Chi-Square Test of Goodness of fit in detail. The two resistors R and Rs are connected in series. The voltage drops across each resistor are measured as $E=10V\pm0.1V$ (1%) and $E_s=1.2V\pm0.005V(0.467\%)$ along with a value of $R_s=0.0066\Omega\pm1/4\%$. From these measurements determine the power dissipated in resistor R and its uncertainty.	07 07
Q.4	(a)	Explain holographic interferometry principle. Explain double exposure holographic interferometry.	07
	(b)	Explain how LASER can be used for surface study.	07

Explain the displacement devices used in CMM. **(b)**

Q.4 Explain the different probe sensors used in CMM. (a)

07 07

Explain briefly methods of image processing. (a)

07

07

Discuss Histogram Concavity technique used for machine vision systems. **(b)**

07

Q.5 Explain computer imaging systems. (a)

Q.5

07 07

Discuss technical difficulties encountered for machine vision systems as far as **(b)** image processing is concern.

OR

OR
